## IN THE CLAIMS

Please amend the claims as follows:

Claims 1-55 (Canceled).

Claim 56 (Currently Amended): A method of making an improved vacuum processing apparatus, comprising:

providing a processing chamber, including

a lower wall;

an upper wall;

a side wall coupled to the lower wall and the upper wall; and

a plurality of pumping ports, formed in one of the lower wall, the upper wall, or the side wall;

connecting a pumping cell, integrally including a vacuum pump and a valve, to a first pumping port;

connecting a [[seal]] <u>lid</u> to a second pumping port such that the [[seal]] <u>lid</u> blocks a gas flow through the second pumping port;

removing the pumping cell from the first pumping port and providing a substitute [[seal]] <u>lid</u> to the first pumping port such that the substitute [[seal]] <u>lid</u> blocks a gas flow through the first pumping port; and

removing the [[seal]] <u>lid</u> from the second pumping port and providing a substitute pumping cell to the second pumping port such that a gas flow through the vacuum processing apparatus is reconfigured by the providing the substitute [[seal]] <u>lid</u> to the first pumping port and the providing the substitute pumping cell to the second pumping port.

Claim 57 (Previously Presented): The method according to claim 56, further comprising:

making the side wall with a height of at most about four inches.

Claim 58 (Previously Presented): The method according to claim 57, further comprising:

making the process chamber of plate stock with a thickness of about four inches.

Claim 59 (Previously Presented): The method according to claim 58, wherein the plate stock is aluminum.

Claim 60 (Previously Presented): The method according to claim 57, further comprising:

making the process chamber via a molding process.

Claim 61 (Previously Presented): The method according to claim 57, wherein said lower wall is a plate and said side wall is a rolled cylinder, and the making the process chamber includes welding the lower wall to the side wall.

Claim 62 (Previously Presented): The method according to claim 57, further comprising:

providing the plurality of pumping ports on the lower wall of the process chamber adjacent to a process chamber volume.

Claim 63 (Previously Presented): The method according to claim 57, further comprising:

providing a chuck assembly in the process chamber; and providing three pumping ports on the lower wall of the process chamber symmetrically spaced about the chuck assembly.

Claim 64 (Currently Amended): The method according to claim 63, further comprising:

connecting three pumping cells to the process chamber,

wherein each one of the three pumping cells are connected to a respective one of the three pumping ports and the three pumping ports being configured to receive said substitute [[seal]] <u>lid</u> in order to reconfigure the gas flow in the vacuum processing apparatus.

Claim 65 (Previously Presented): The method according to claim 57, further comprising:

providing a chuck assembly in the process chamber; and

providing two pumping ports on the lower wall of the process chamber symmetrically spaced about the chuck assembly on opposing sides thereof.

Claim 66 (Currently Amended): The method according to claim 65, further comprising:

connecting two pumping cells to the process chamber,

wherein each one of the two pumping cells are connected to a respective one of the two pumping ports and the two pumping ports being configured to receive said substitute [[seal]] <u>lid</u> in order to reconfigure the gas flow in the vacuum processing apparatus.

Claim 67 (Previously Presented): The method according to claim 56, further comprising:

providing a chamber liner in the process chamber configured to displace open volume within the process chamber.

Claim 68 (Previously Presented): The method according to claim 56, further comprising:

providing an upper electrode to facilitate the formation of plasma in the process chamber.

Claim 69 (Currently Amended): The method according to claim 56, wherein the substitute [[seal]] <u>lid</u> provided to the first pumping port is the [[seal]] <u>lid</u> removed from the second pumping port, and

the substitute pumping cell provided to the second pumping port is the pumping cell removed from the first pumping port.

Claim 70 (Currently Amended): The method according to claim 56, wherein the removing the [[seal]] <u>lid</u> from the second pumping port includes removing the [[seal]] <u>lid</u> such that the [[seal]] <u>lid</u> does not contact the lower wall, the upper wall, or the side wall.